

GR 2814



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TRANSMITTAL FORM <i>(to be used for all correspondence after initial filing)</i>		Application Number	09/327,469
		Filing Date	June 8, 1999
		First Named Inventor	Shunpei YAMAZAKI
		Group Art Unit	2814
		Examiner Name	Ginette PERALTA
Total Number of Pages in This Submission		Attorney Docket Number	740756-1982

ENCLOSURES (check all that apply)		
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PATENT *Sunder*
740756-1982

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re PATENT application of:

Shunpei YAMAZAKI

Application No.: 09/327,469

Filed: June 8, 1999

For: SEMICONDUCTOR DEVICE AND
METHOD OF MANUFACTURING
THE SAME

) Art Unit: 2814
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) Examiner: Ginette PERALTA
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CERTIFICATE OF MAILING

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AMENDMENT

Commissioner of Patents
Washington, D.C. 20231

June 28, 2001

Dear Sir:

In response to the Examiner's non-Final Office Action mailed March 28, 2001, please consider the following amendments and remarks in connection with the above-identified application.

IN THE CLAIMS:

Please cancel claim 1 without prejudice or disclaimer of the subject matter disclosed therein.

Please amend claims 2, 3, 9, 10, 20, and 21 as follows:

2. (Amended) A method of manufacturing a semiconductor device, comprising:
- a first step of forming a semiconductor film;
 - a second step of holding a catalytic element that promote the crystallization of said semiconductor film in contact with said semiconductor film; and
 - a third step of irradiating a laser beam shaped in a rectangle or a square while moving the laser beam from one side of said semiconductor film toward another side thereof to sequentially crystallize said semiconductor film to form a crystalline semiconductor film,